

PATENT APPLICATION

In re Application of:)
Akiyoshi SUZUKI et al.) Previous Examiner: F. Braun
Application No.: Divisional of Appln. No. 09/810,488,)
filed March 19, 2001) Previous Group Art Unit: 2852
Filed: October 17, 2003)
For: EXPOSURE APPARATUS AND DEVICE)
MANUFACTURING METHOD INCLUDING)
CHANGING A PHOTO-INTENSITY)
DISTRIBUTION OF A LIGHT SOURCE AND)
ADJUSTING AN ILLUMINANCE)
DISTRIBUTION ON A SUBSTRATE IN)
ACCORDANCE WITH THE CHANGE)
(As Amended))

INFORMATION DISCLOSURE STATEMENT

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document listed on the enclosed PTO-1449 form. Copies of the listed documents are also enclosed.


These documents were cited during prosecution of copending parent application no. 09/810,488, filed March 19, 2001.

Applicants request that the above information be considered by the Examiner and that a copy of the enclosed PTO-1449 form be initialed and returned indicating that such information has been considered.

This Information Disclosure Statement is being filed before the issuance of a first Office Action on the merits. Therefore, no fee under 37 C.F.R. 1.97(c)(2) is believed due. Nevertheless, the Commissioner may charge Deposit Account No. 06-1205, should any fee be due for filing this paper.

Applicants' undersigned attorney may be reached in our Washington D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



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SEW/eab

FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) October 17, 2003				ATTY DOCKET NO. 00684.00152.13		APPLICATION NO. Divisional of Appln. No. 09/819,488, filed March 19, 2001	
				APPLICANT Akiyoshi SUZUKI et al.			
				FILING DATE October 17, 2003		GROUP 2852	
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		US-3,729,252	04/24/1973	Nelson	350	162 SF	
		US-3,776,633	12/04/1973	Frosch et al.	355	132	
		US-3,887,816	06/03/1975	Colley	350	571	
		US-4,497,015	01/29/1985	Konno et al.	362	268	
		US-4,498,742	02/12/1985	Uehara	350	523	
		US-4,521,082	06/04/1985	Suzuki et al.	350	405	
		US-4,619,508	10/28/1986	Shibuya et al.	353	122	
		US-4,634,240	01/06/1987	Suzuki et al.	350	508	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
		61-91662	05/09/1986	Japan			Abstract
		0 346 844	06/13/1989	Europe			
		0 293 643	05/10/1988	Europe			
		0 437 376	01/11/1991	Europe			
		0 486 316	11/15/1991	Europe			
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
		Pol, Victor, et al. "Excimer Laser Based Lithography: A Deep-Ultraviolet Wafer Stepper for VLSI Processing," <u>Optical Engineering</u> , Vol. 26, No. 4, pp. 311-318, April 1987.					
		Yang, S.T., et al. "Effect of Central Obscuration on Image Formation in Projection Lithography," <u>SPIE Vol. 1264 Optical/Laser Microlithography III</u> , pp. 477-485, 1990.					
		H cht-Zajac, <u>Optics</u> , 1 st Edition, p. 117, 1974.					
EXAMINER				DATE CONSIDERED			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		US-4,645,924	02/24/1987	Suzuki et al.	250	236	
		US-4,668,077	05/26/1987	Tanaka	355	30	
		US-4,780,747	10/25/1988	Suzuki et al.	355	68	
		US-4,851,882	07/25/1989	Takahashi et al.	355	46	
		US-4,924,257	05/08/1990	Jain	355	53	
		US-4,931,830	06/05/1990	Suwa et al.	355	71	
		US-4,947,030	08/07/1990	Takahashi	250	201.1	
		US-4,988,188	01/29/1991	Ohta	353	122	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
		39 33 308 A1	05/03/1990	Germany			No
		28 35 363 A1	03/13/1980	Germany			No
		40 07 069 A1	09/20/1990	Germany			No
		61-210627	09/18/1986	Japan			Abstract
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
		Intl. Cl., 5 th Edition, Vol. 7, Section G, pp. 68 and 72, 1989.					
		Glatzel, Erhard. "New Lenses for Microlithography," SPIE, Vol. 237, p. 310, International Lens Design Conference (OSA), 1980.					
		European Search Report regarding 01200962.7 dated May 31, 2001.					
		European Search Report regarding 97200014.5 dated May 20, 1997.					
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*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		US-5,061,956	10/29/1991	Takubo et al.	355	55	
		US-5,119,390	06/02/1992	Ohmori	372	25	
		US-5,144,362	09/01/1992	Kamon et al.	355	53	
		US-5,153,419	10/06/1992	Takahashi	250	201.1	
		US-5,160,962	11/03/1992	Miura et al.	355	53	
		US-5,237,367	08/17/1993	Kudo	355	67	
		US-5,245,384	09/14/1993	Mori	355	67	
		US-5,251,067	10/05/1993	Kamon	359	628	
		US-5,253,040	10/12/1993	Kamon et al.	356	399	
		US-5,264,898	11/23/1993	Kamon et al.	355	67	
		US-5,286,963	02/15/1994	Torigoe	250	201.2	
		US-5,287,142	02/15/1994	Kamon	355	53	
		US-5,296,892	03/22/1994	Mori	355	67	
		US-5,357,311	10/18/1994	Shiraishi	355	53	
		US-6,271,909	08/07/2001	Suzuki et al.	355	53	
		US-4,988,188	01/29/1991	Ohta	353	122	
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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
		Affidavit of Carl Zeiss in the opposition to EP 0 183 827 by Canon KK, 1994					
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